IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: 10/711,649 Applicant: Kawamura et al.

Art Unit: 2813

Title: A METHOD FOR SUPERCRITICAL CARBON DIOXIDE

PROCESSING OF FLUORO-CARBON FILMS

Attorney Docket: SSIT-114
Confirmation No. 5648

Cincinnati, OH March 30, 2007

Mail Stop AF Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir

AMENDMENT AFTER FINAL

This paper is responsive to the final Office Action mailed October 30, 2006. The Examiner has indicated that claims 1, 2, 5-15 and 17-26 are pending in the application, claims 3, 4, and 16 are withdrawn from consideration, and claims 1, 2, 5-15, and 17-26 are rejected. The present response includes the following:

Amendments to the Specification: None
Amendments to the Claims: None
Amendments to the Abstract: None
Amendments to the Drawings: None
Remarks: Pages 2-7
Attachments: None